



**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Koichi KANAYA et al.

Group Art Unit: 1762

Application No.: 10/565,653

Examiner: K. CHEN

Filed: January 24, 2006

Docket No.: 126247

For: VAPOR DEPOSITION APPARATUS AND VAPOR DEPOSITION METHOD

**AMENDMENT FILED WITH RCE**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the October 2, 2007 Office Action, the period for reply being extended by the Petition for Extension of Time filed herewith, and after entry of the Request for Continued Examination (RCE) filed herewith, please consider the following:

**Amendments to the Claims** as reflected in the listing of claims; and

**Remarks.**